

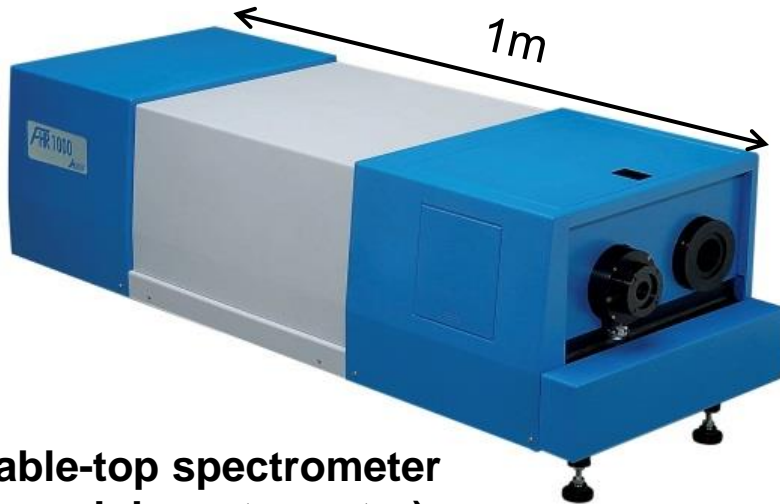
# Integrated, scalable spectral sensors

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*Institute for Photonic Integration*  
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# Our dream

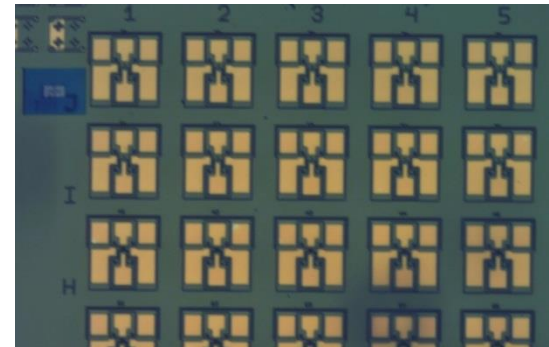
Replace this:



**Table-top spectrometer  
(or minispectrometer)**

- Bulky
- Expensive (1'000-10'000 EUR)
- High-performance
- General purpose
- Single-pixel

With this:

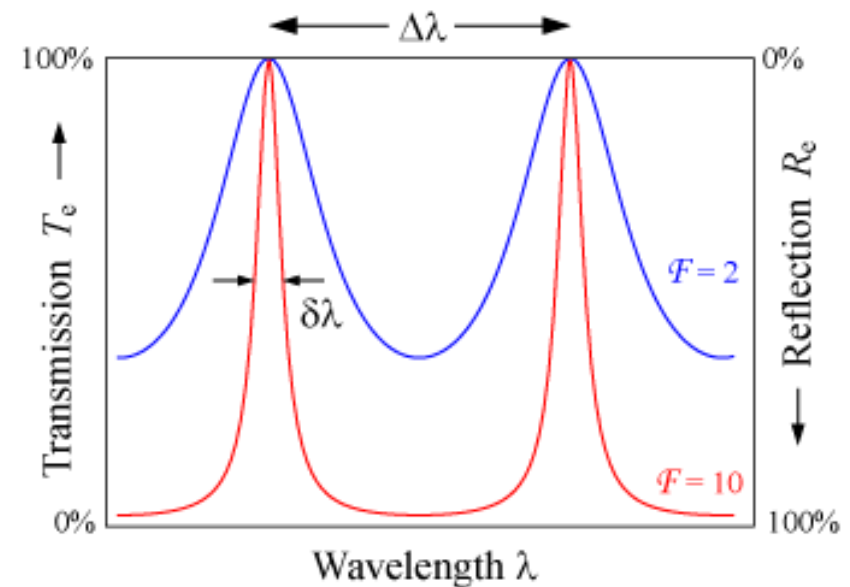
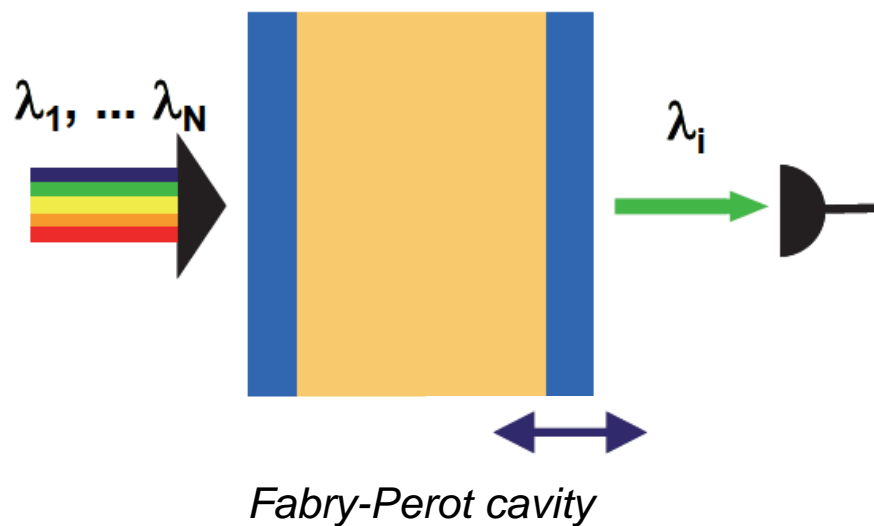


**Microspectrometer**

- Integrated
- Cheap (10-100 EUR)
- High-performance
- Dedicated to specific application
- Arrays

# How to integrate a spectrometer

## Getting spectral information by filtering

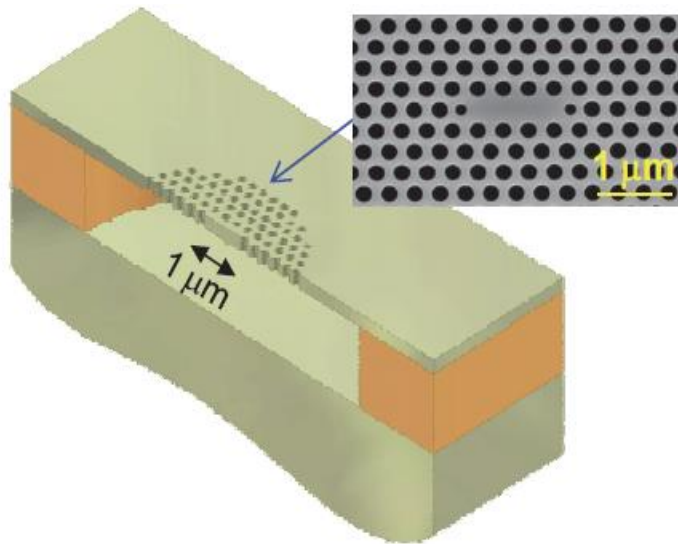


(resolution determined by the linewidth)

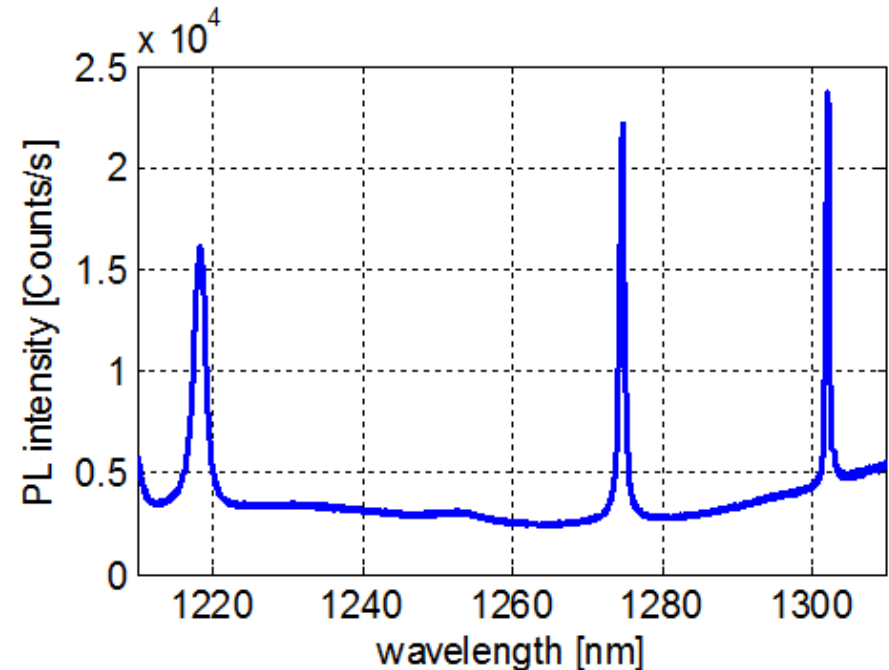
### **Key functionalities:**

- 1) Filtering
- 2) Actuation
- 3) Detection

# Filtering with photonic crystal cavities



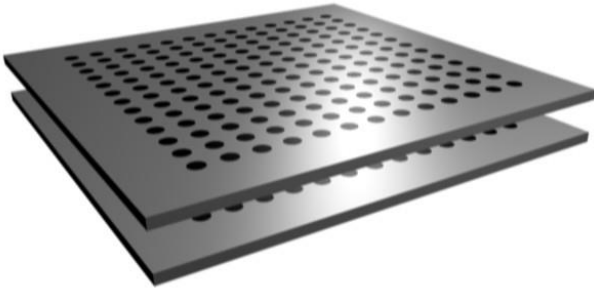
*Photonic crystal slab*



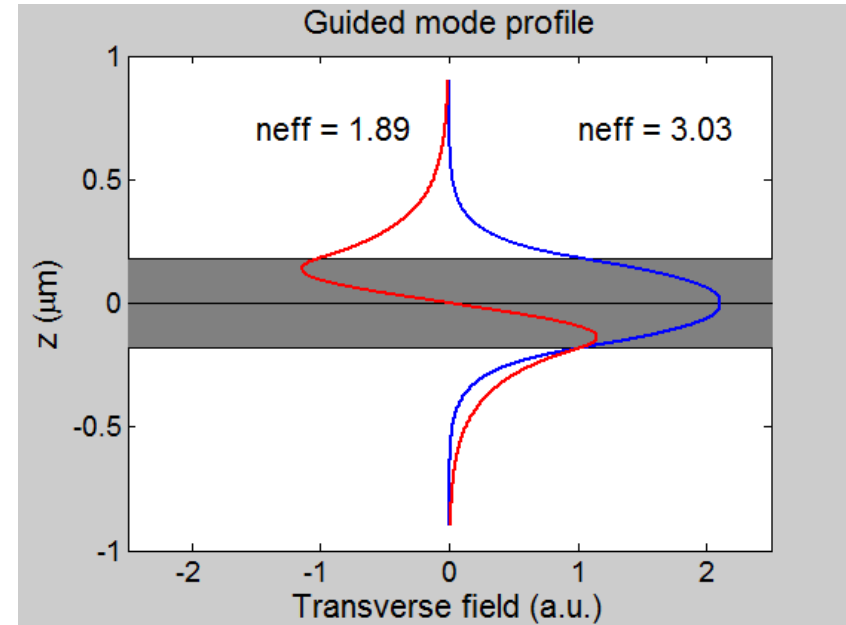
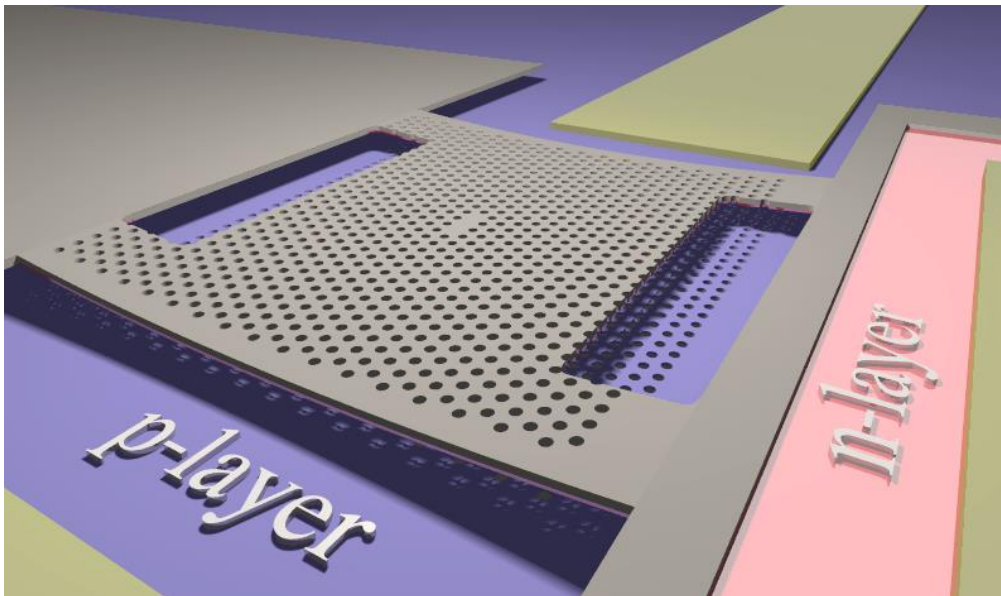
- Very **high Q** factor possible (up to  $10^6$ )
- Small Volume  $\sim \lambda^3 \rightarrow$  **Large free spectral range possible**
- Light mass ( $\sim$  **10 picograms**)  $\rightarrow$  high speed

# Cavity actuation

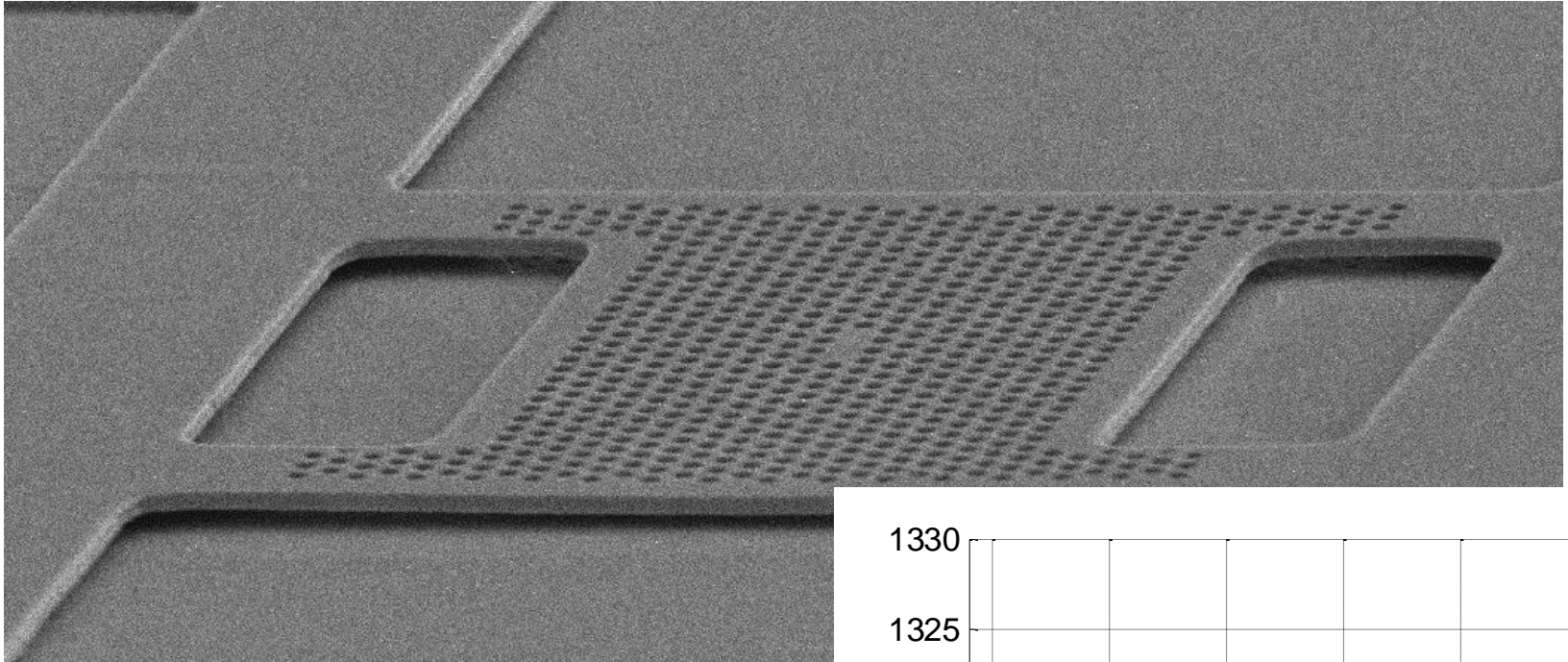
Double-membrane structures:  
Change *effective index*



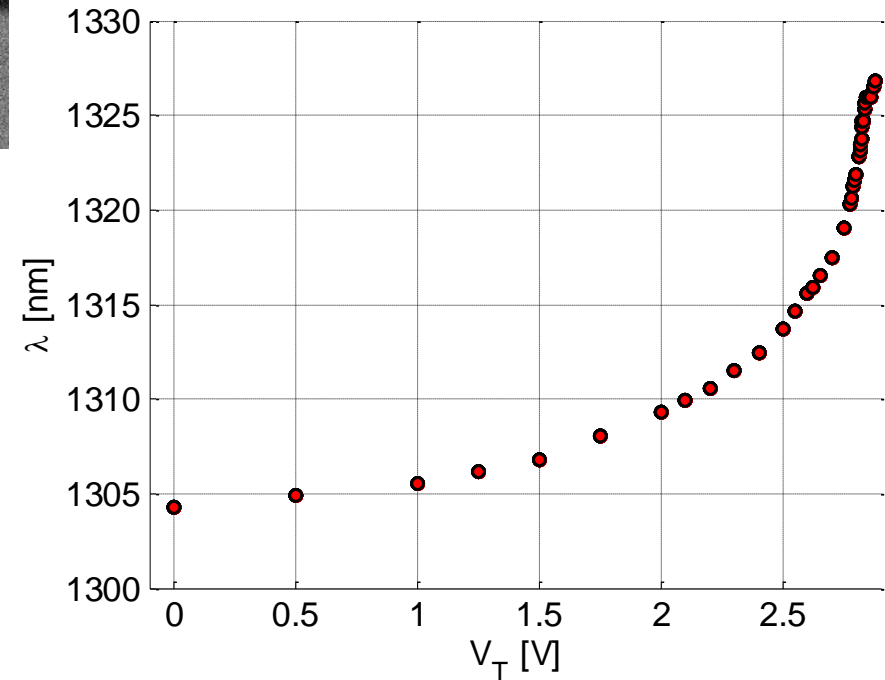
Electrostatic actuation:



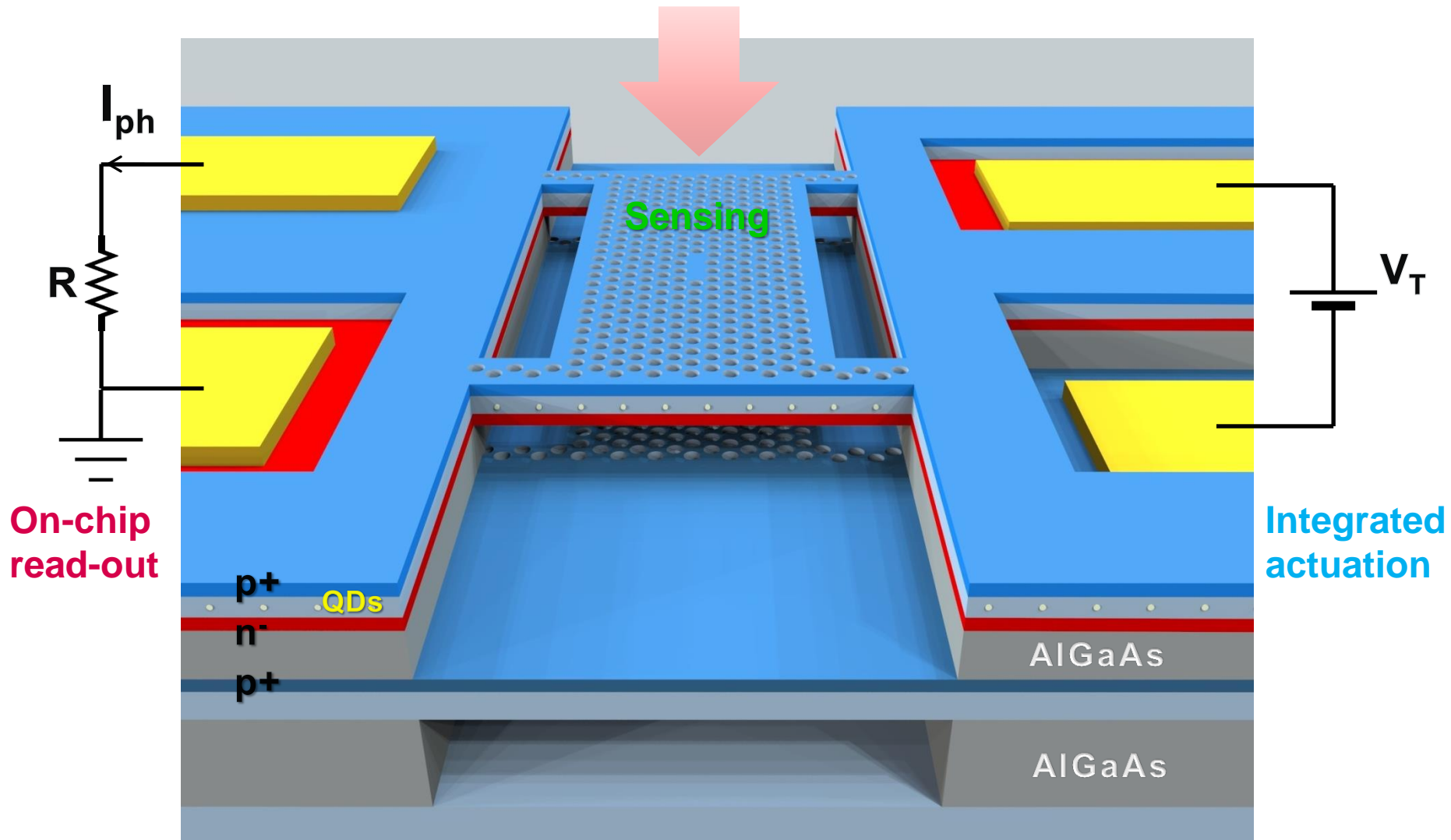
# Nanomechanical cavities



**Experimental tuning range:  
20-30 nm**

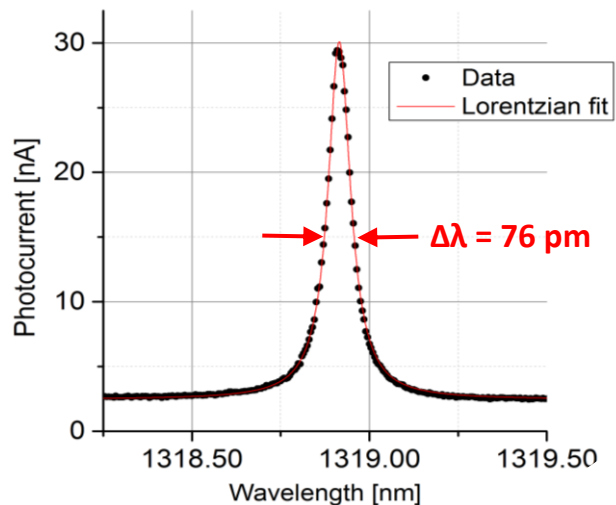


# Integrated microspectrometer

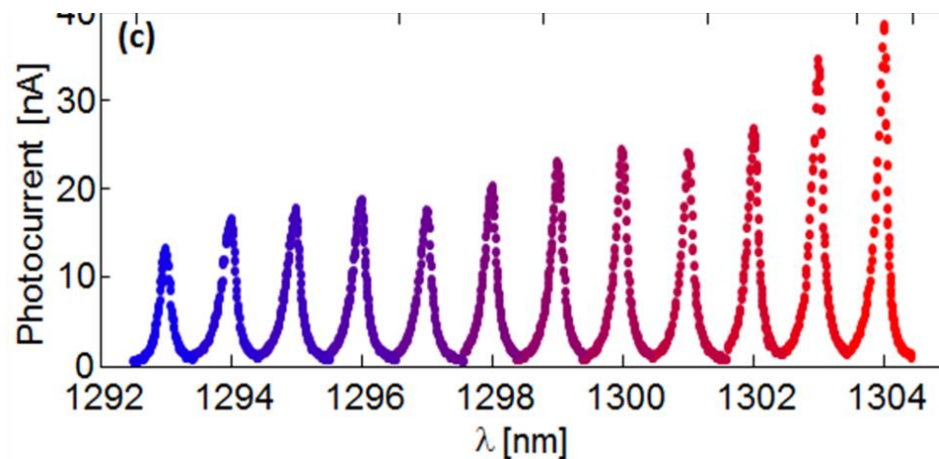


# Microspectrometers: Results

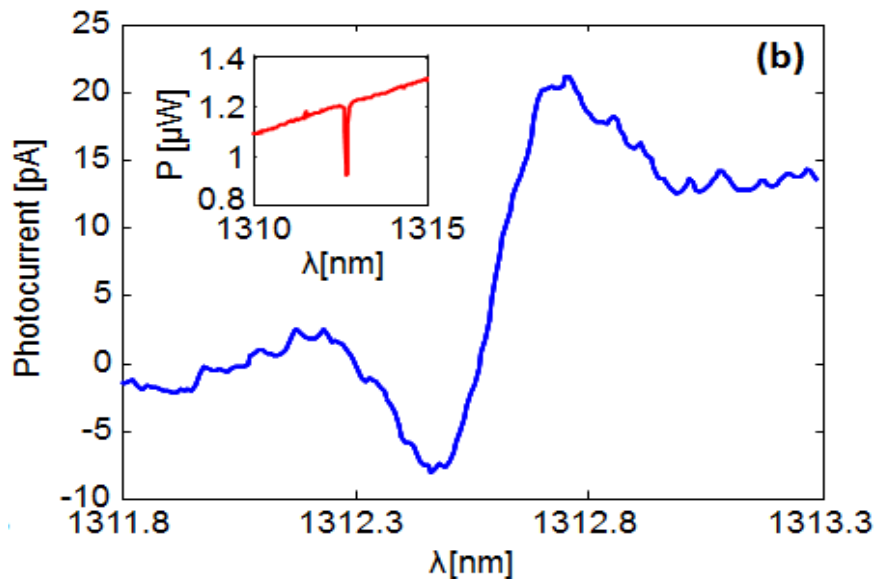
Sharp optical resonances:



Tuning  $\Rightarrow$  Spectrum



HF absorption line (16 pm):



Example of application:  
Gas sensing



# Microspectrometer: Perspectives

Present devices offer high resolution (100 pm) but low spectral range (20 nm)

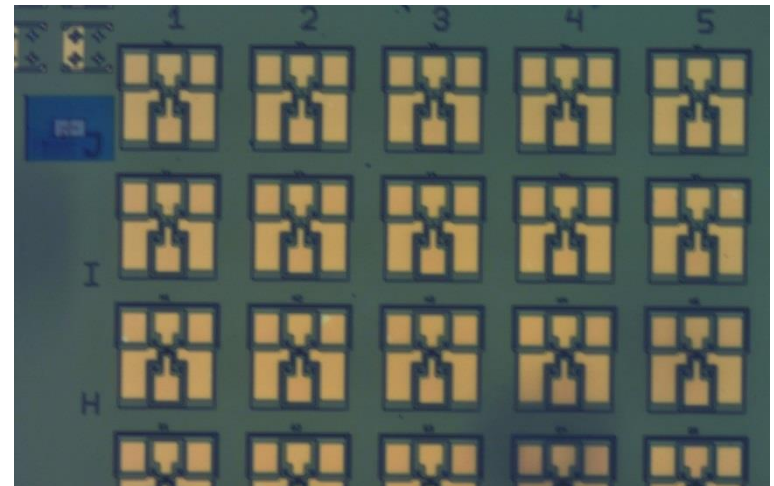
Our next goal: Microspectrometer with 0.5-1 nm resolution, 200 nm spectral range in the 1500-2000 nm region

## Applications:

- Mobile healthcare (monitoring of glucose, triglycerides, ...)
- Gas sensing
- etc

## Notes:

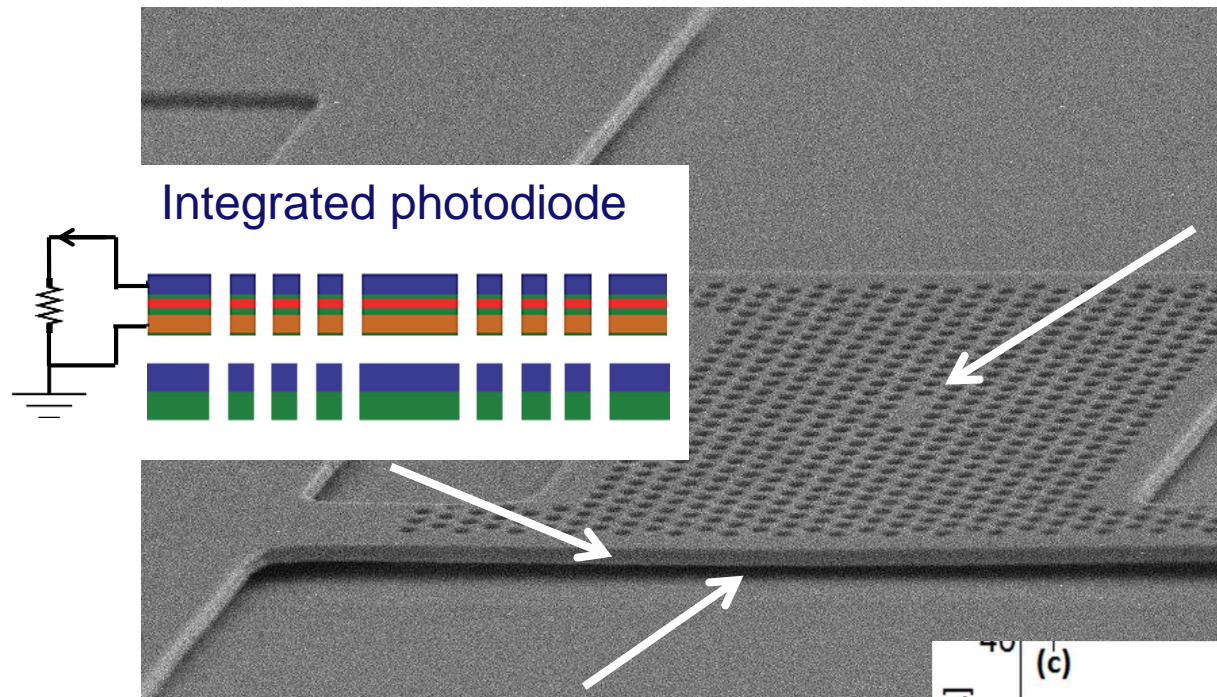
- Light source and spectrometer can be integrated and fitted in a smartphone
- Imaging arrays can be fabricated
- Concept can be extended to other types of optical detectors





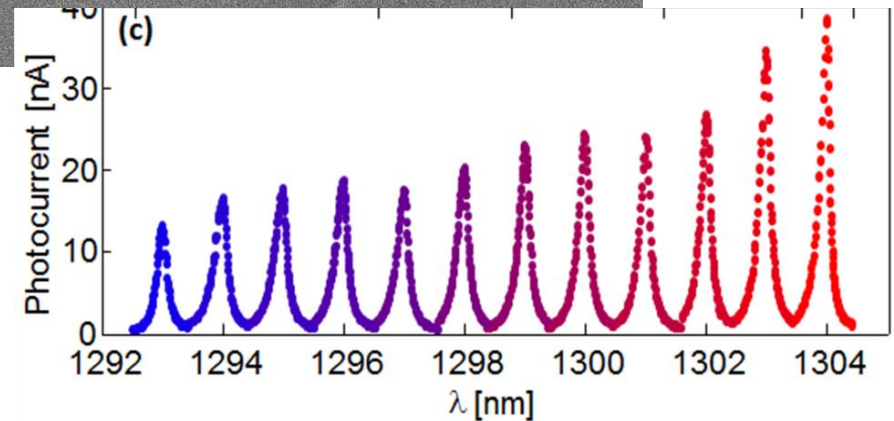
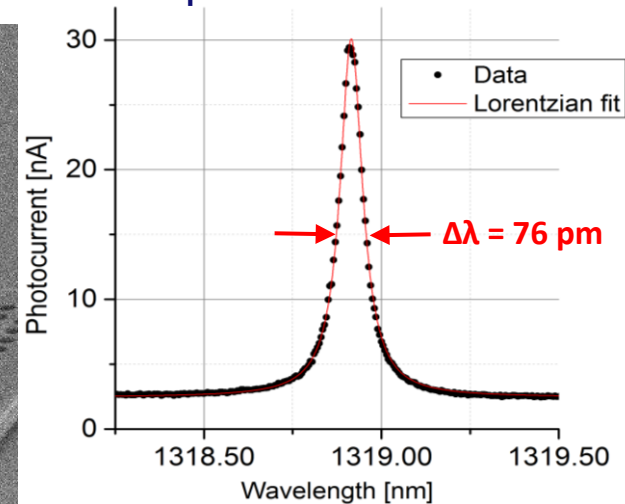
# PSN: Nano-opto-electro-mechanical systems

## Electromechanically-tuneable photonic crystal cavity:



Tuning by electromechanical actuation:

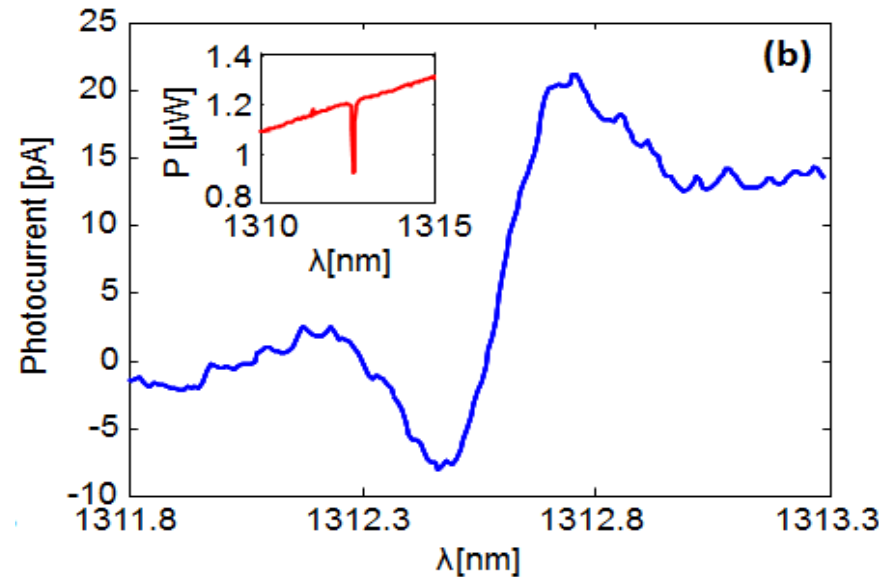
### Optical resonance



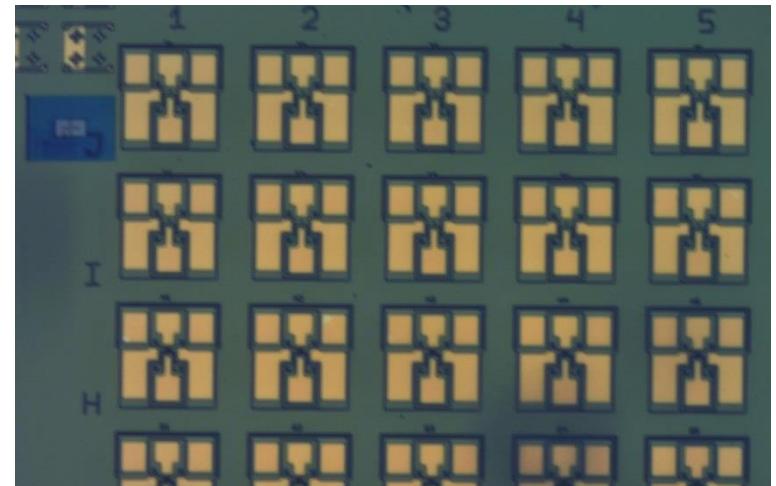
# NOEMS: Application as microspectrometers

- Can measure emission or absorption lines
- Resolution down to  $100 \text{ fm}/(\text{Hz})^{0.5}$

HF absorption line (16 pm):



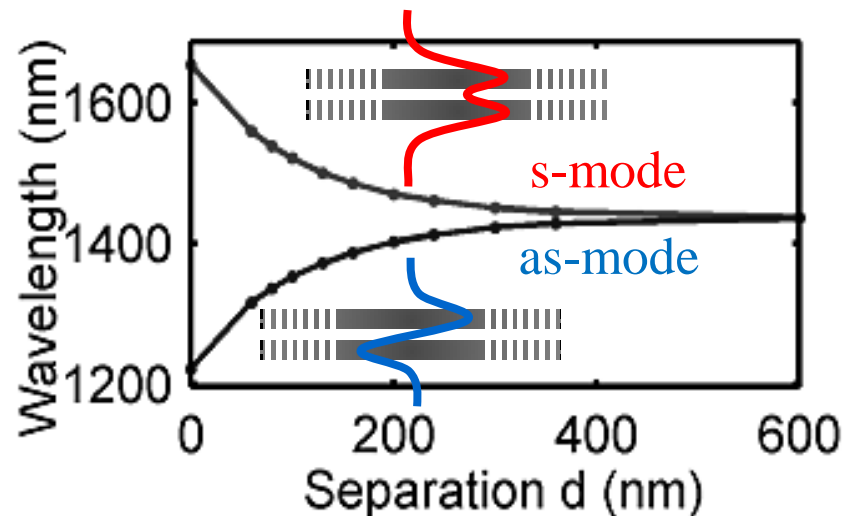
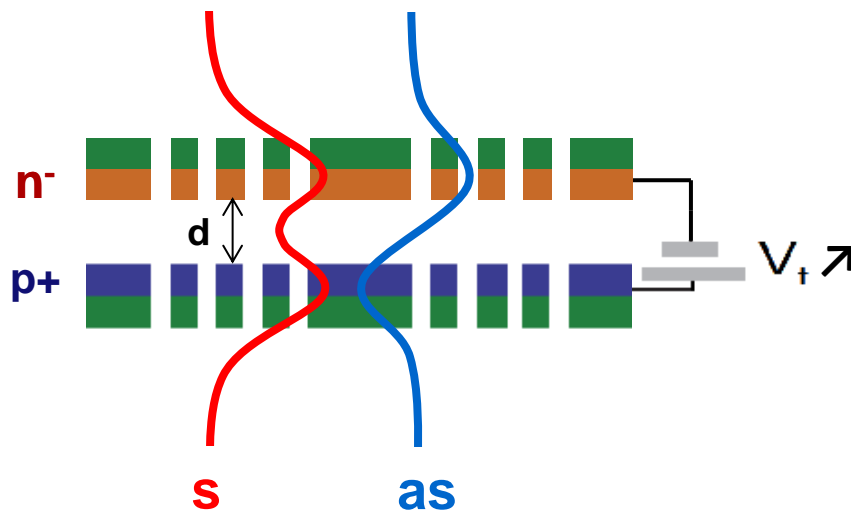
- Fully-integrated, mass-manufacturable



## 2) Nano-opto-electro-mechanical actuation

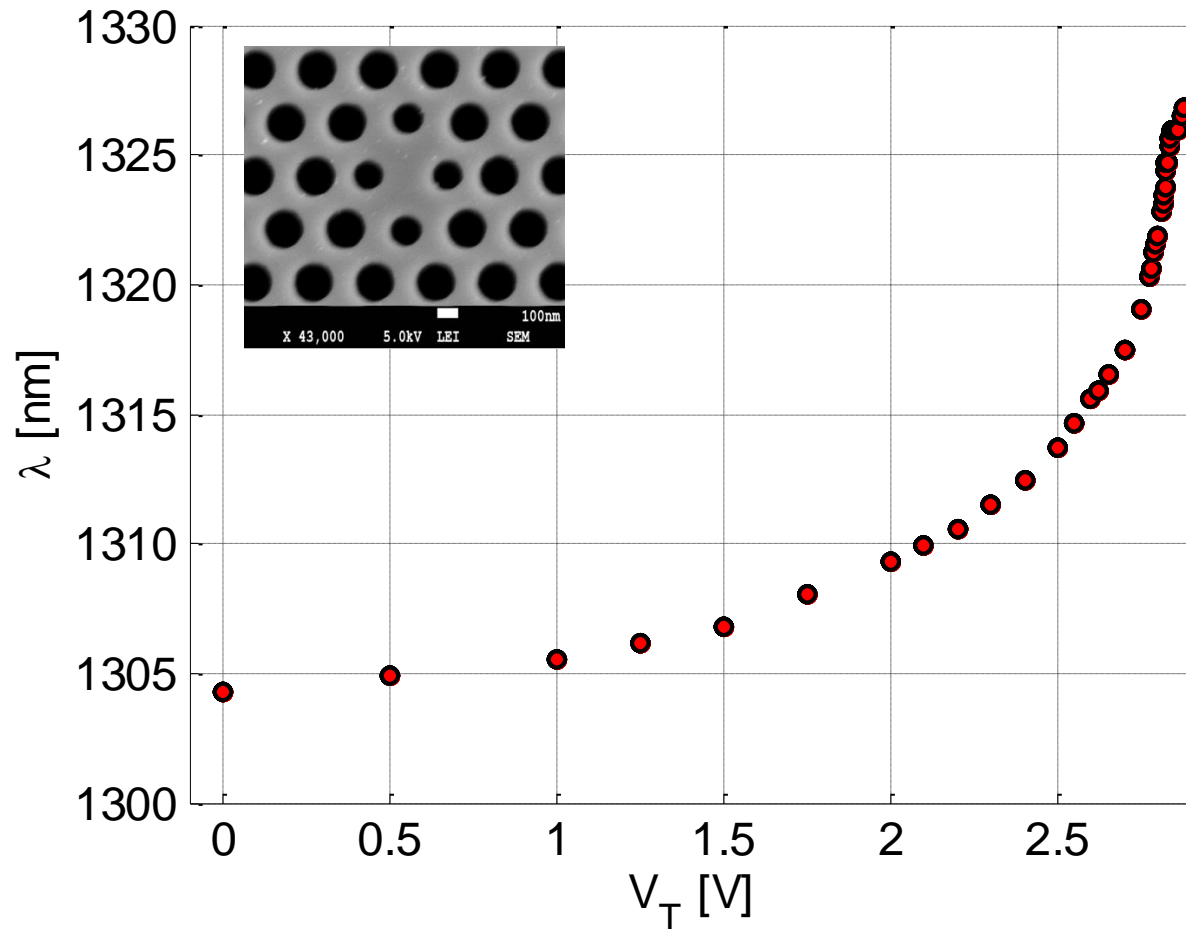
### Double-membrane photonic crystal

- Modes hybridize and form supermodes
- Changing separation tunes the supermodes
- Electrostatic actuation via p-i-n junction



# Nanomechanical tuning: experimental results

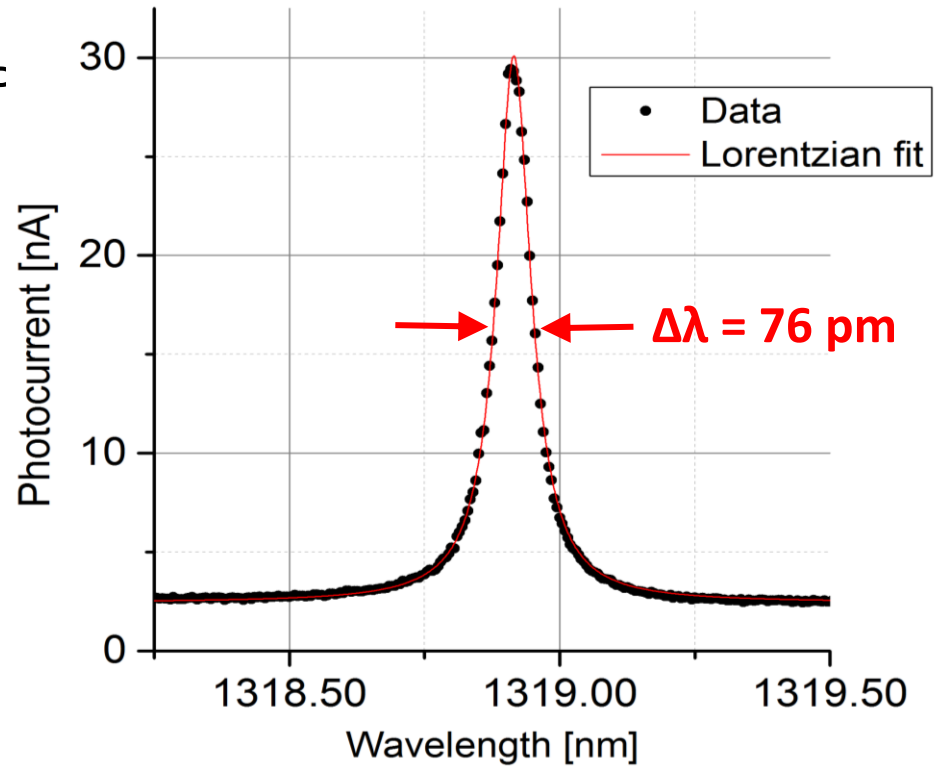
23 nm tuning of monopole mode in H0 cavity:



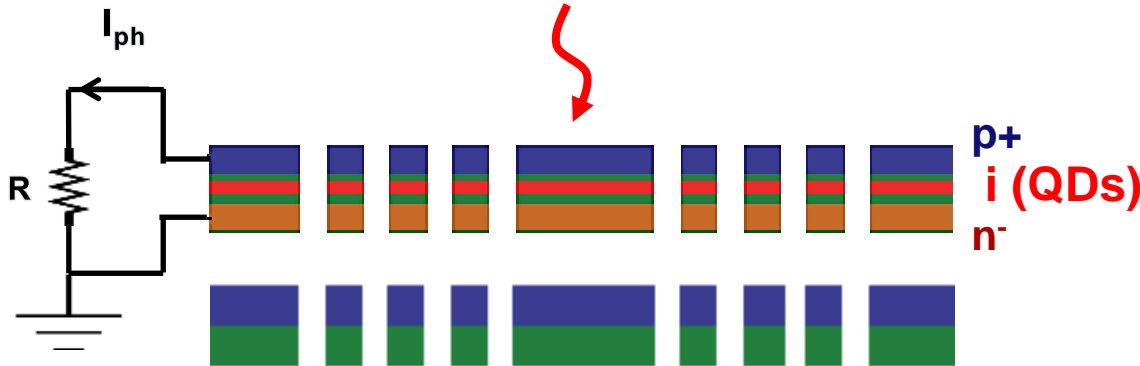
# 3) Detection

- **Absorber:** Quantum dots inside the F
- Vertical **P-i-N photodiode**  
FWHM = **76 pm** → **Q = 17200**  
*(comparable to a table-top spectrometer)*

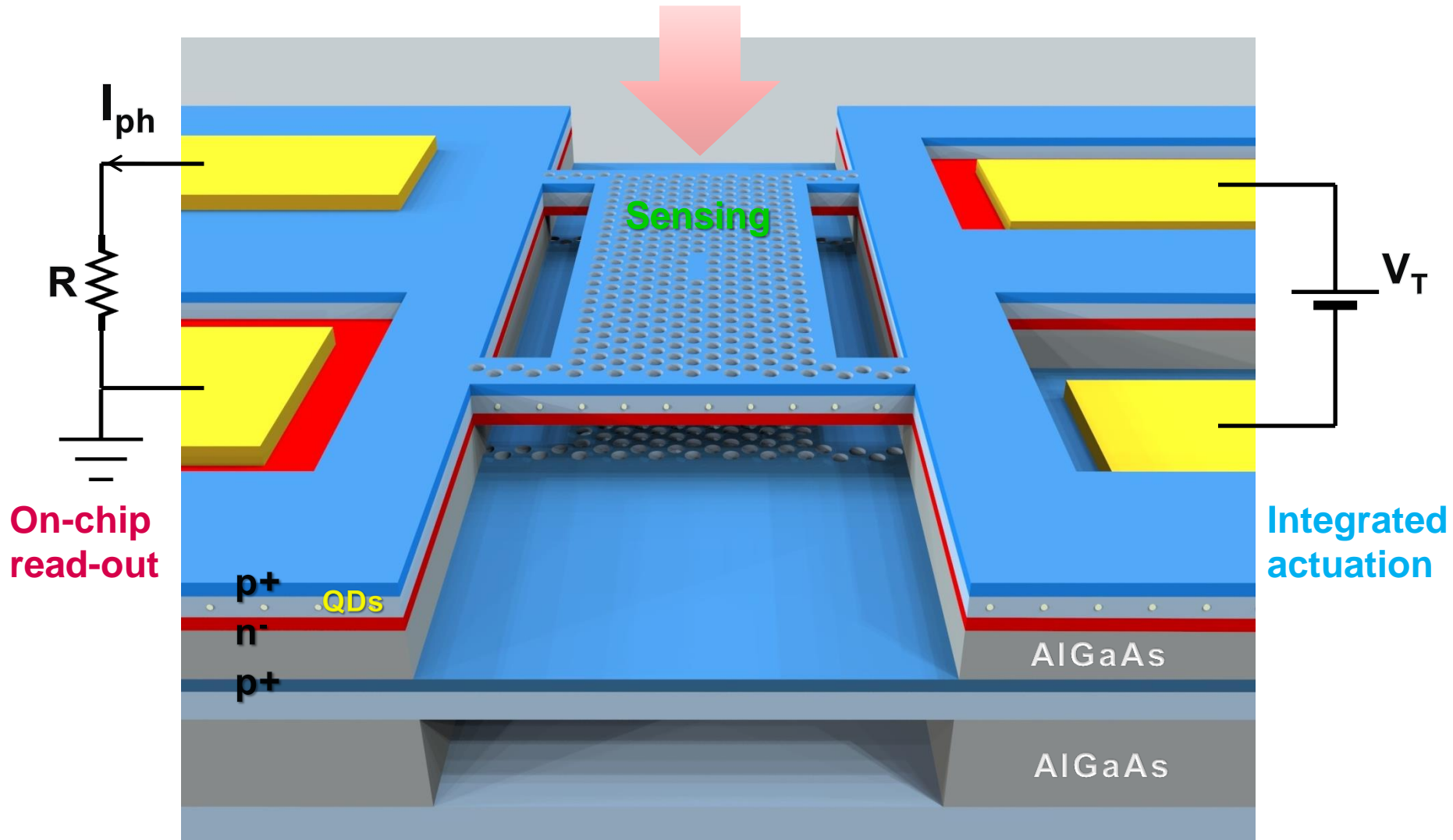
Responsivity up to **20 mA/W**



Light resonant with the cavity

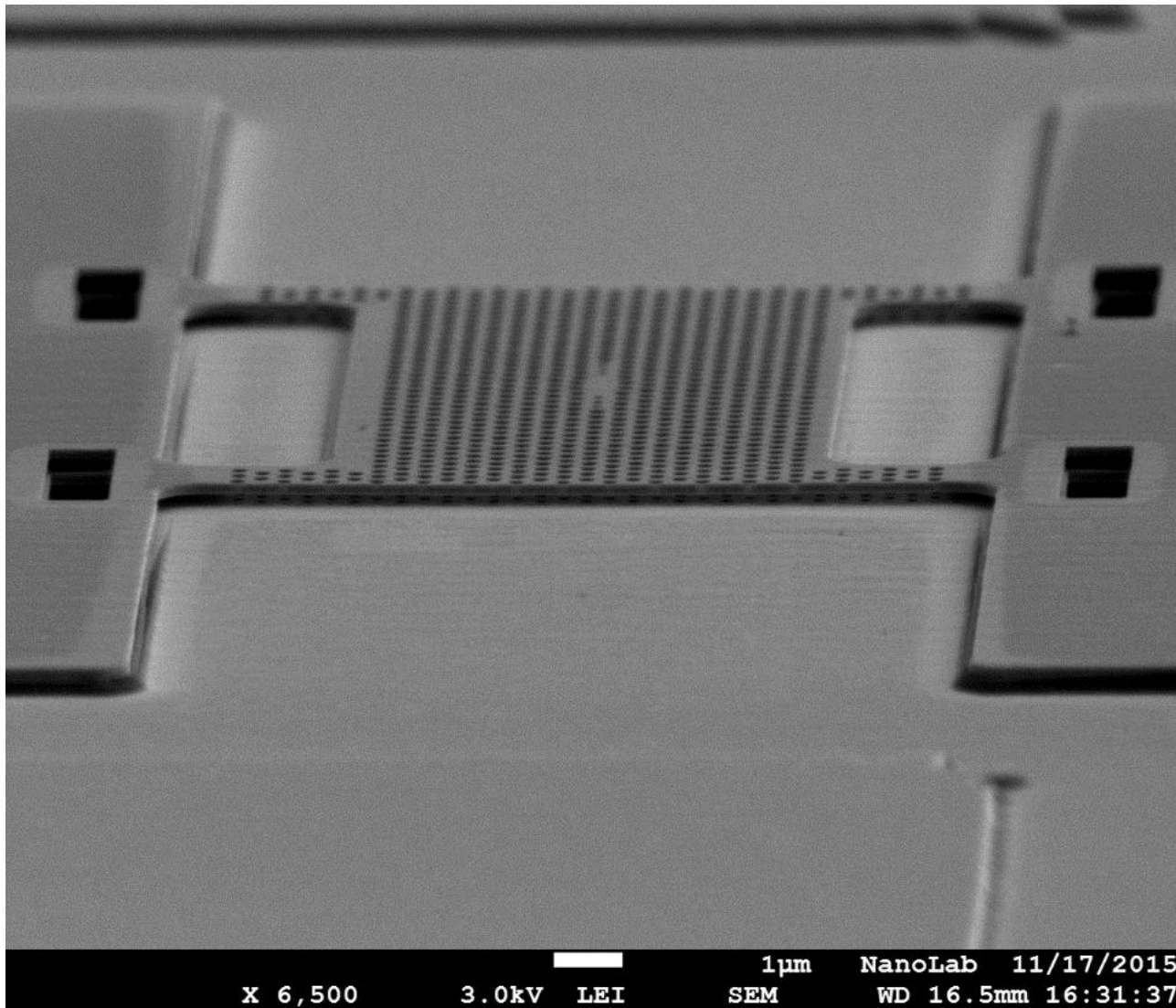


# Concept: Detector + Tuneable Filter





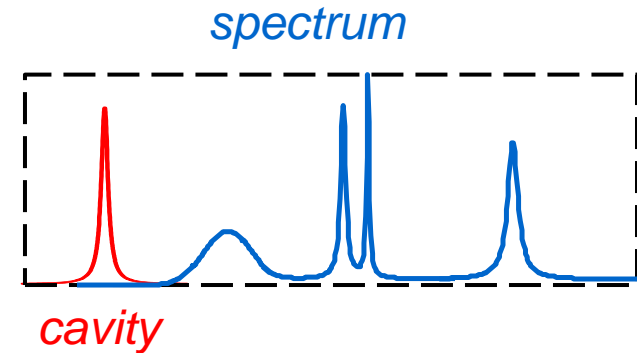
# Fabricated structure



# Sensing: Modes of operation

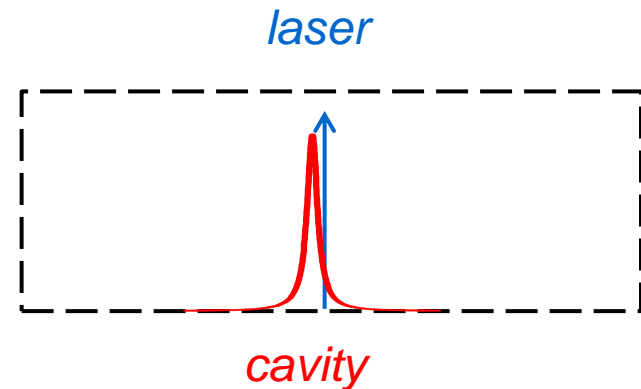
## Spectrometer action (tuneable filter):

- Changing **Voltage** changes  $\lambda$
- Incoming light read as photocurrent

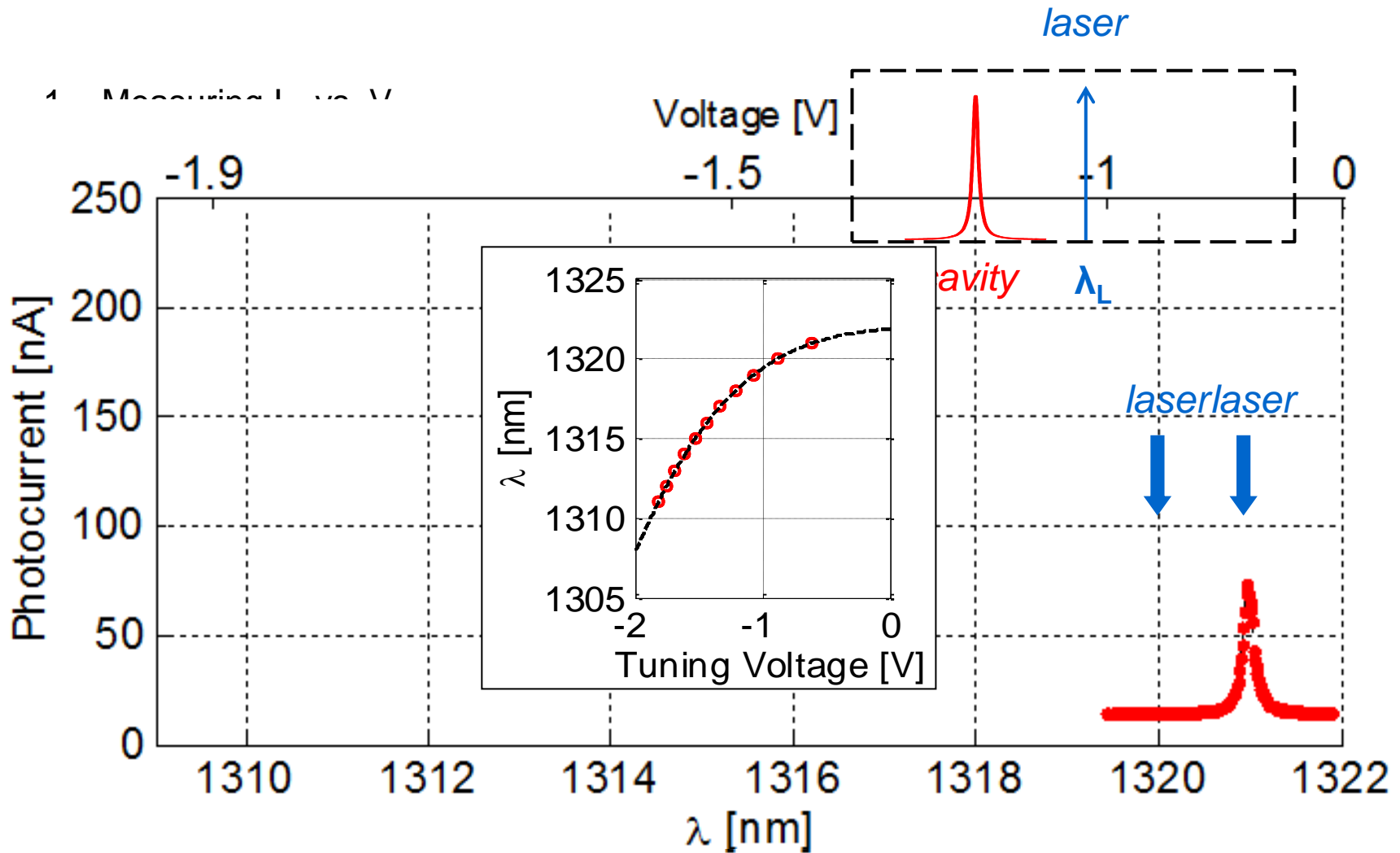


## Optomechanical displacement sensor:

- **Displacement** transduced as a small change in photocurrent



# $\mu$ –spectrometer demonstration

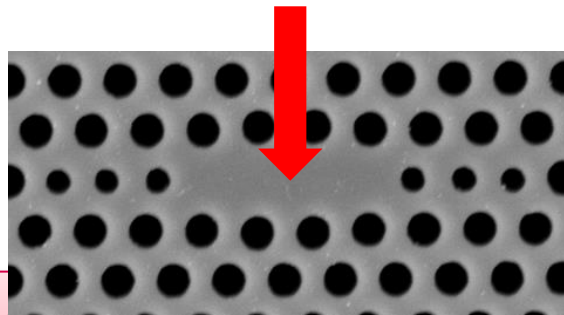
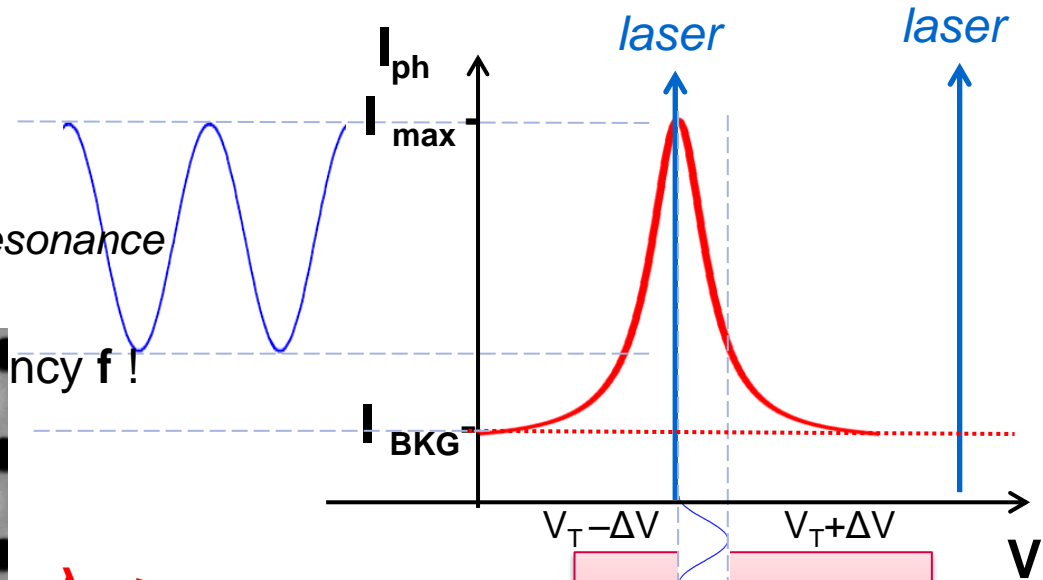


- Resolution  $\sim 150$  pm
- Responsivity changes due to changing field overlap with QDs

# Signal and background in spectroscopy

○  $S/BKG = I_{\max} / I_{BKG} < 20$

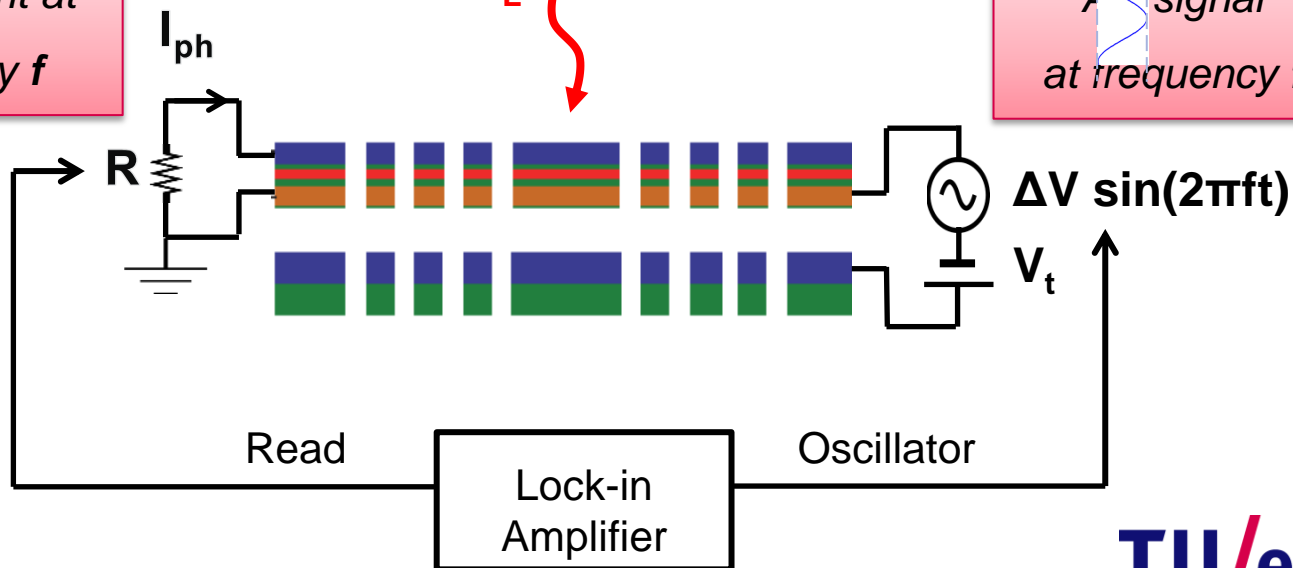
Limited by the absorption of the dots outside of the cavity resonance



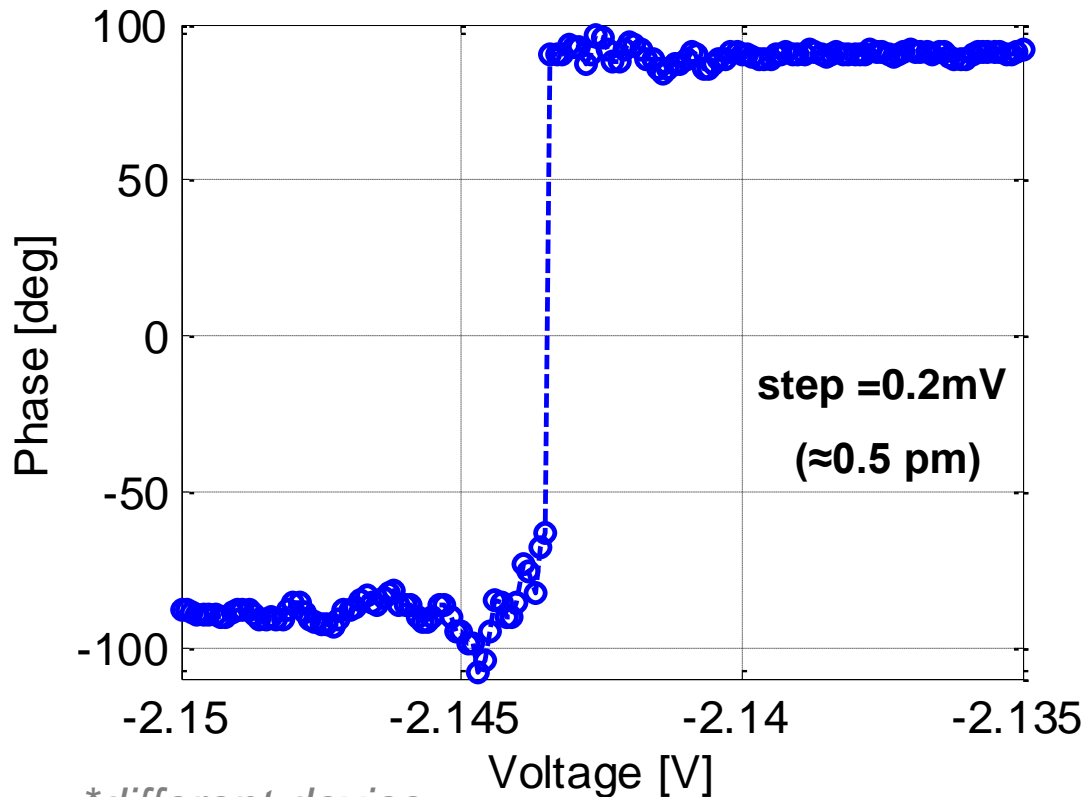
Photocurrent at frequency  $f$

$\lambda_L$

A signal at frequency  $f$



# Demonstration of background suppression



*\*different device*

**Additional advantage:  
Higher wavelength resolution on a single line**

Standard technique (DC):

$$S/BKG = 7 \text{ dB}$$

Resonance modulation scheme  
(DC + AC):

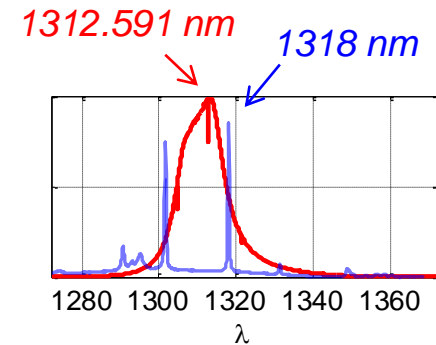
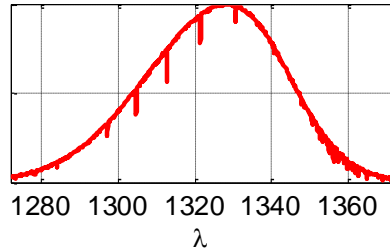
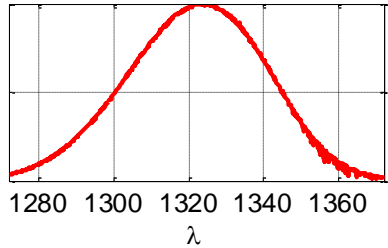
$$S/BKG = 30 \text{ dB}$$

Ultimate resolution is limited  
by noise:

$$\delta\lambda_{min} = \frac{\delta I_{noise}}{\frac{dI}{d\lambda}} \sim 0.1 \text{ pm}$$

# Application of microspectrometer in gas sensing

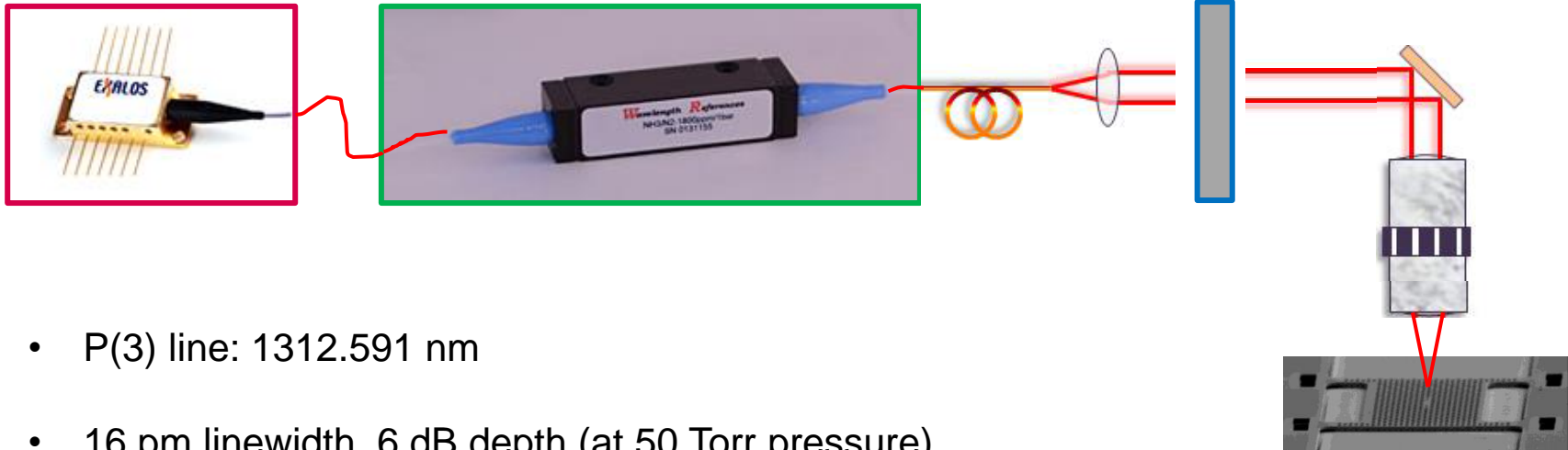
## Measuring HF absorption lines in O-band



SLED

HF gas cell

filter

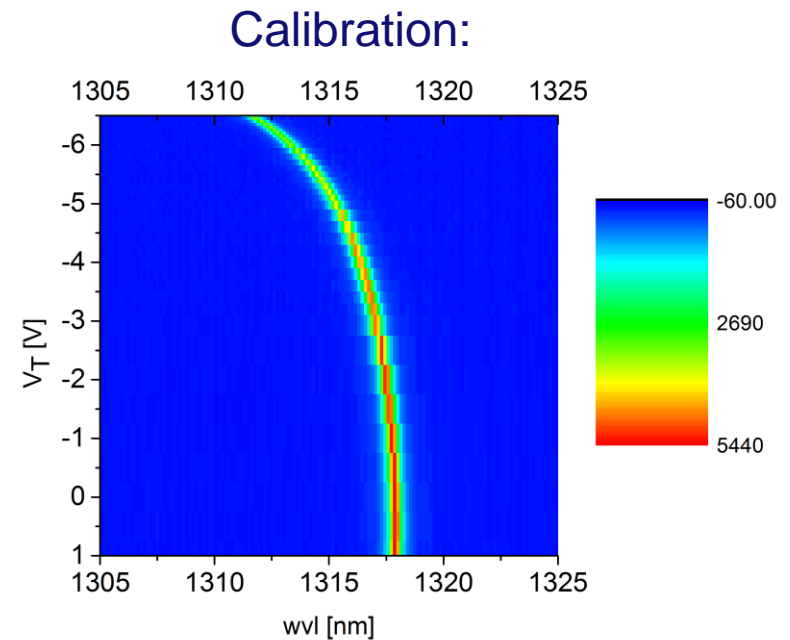
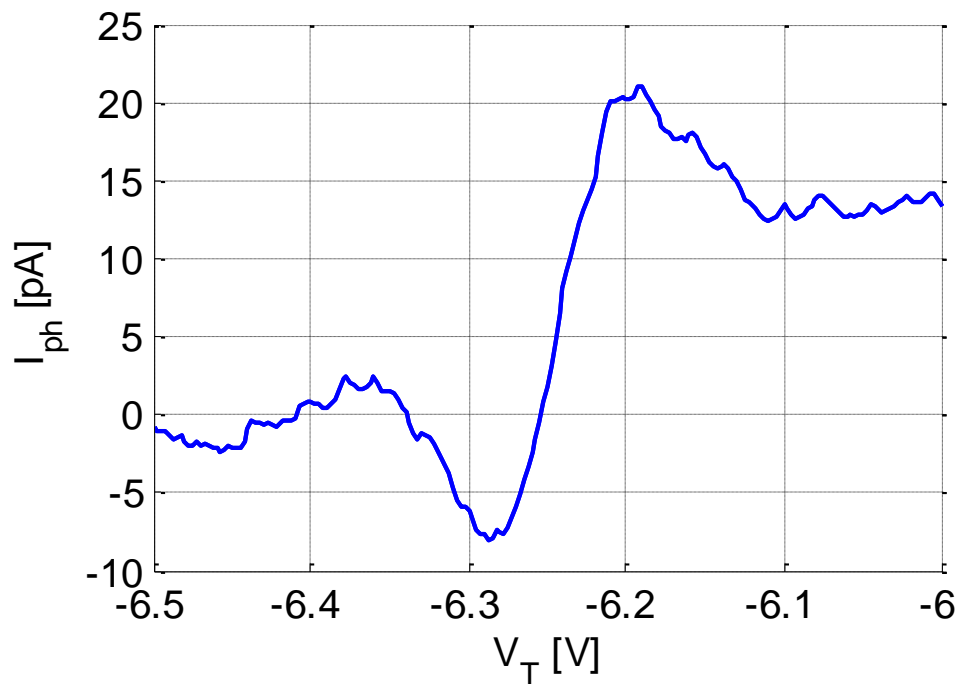


- P(3) line: 1312.591 nm
- 16 pm linewidth, 6 dB depth (at 50 Torr pressure)
- Use of resonance modulation scheme is crucial!

# Gas sensing: Measurements

Excitation: SLED + HF cell + filter (1310 nm)

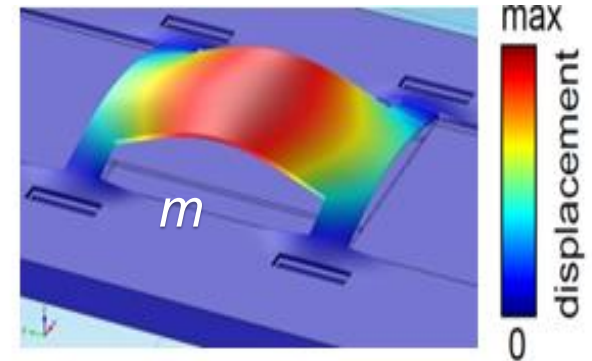
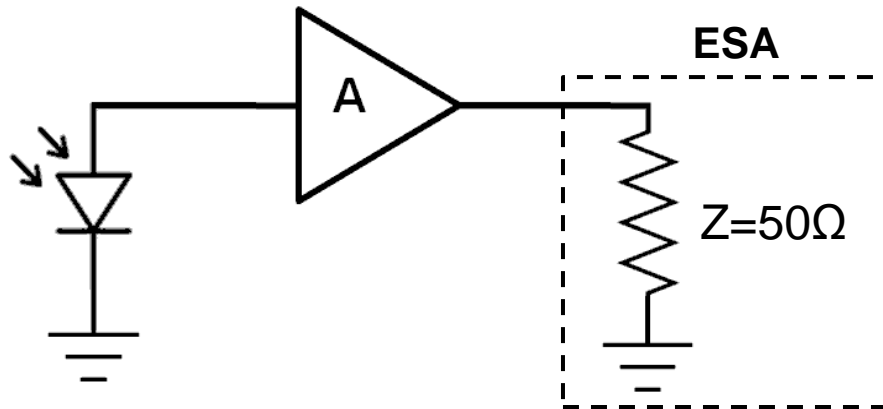
Detection: cavity mode sweeping



*HF absorption line P(3) @ 1312.59 nm detected*

# Displacement sensor demonstration

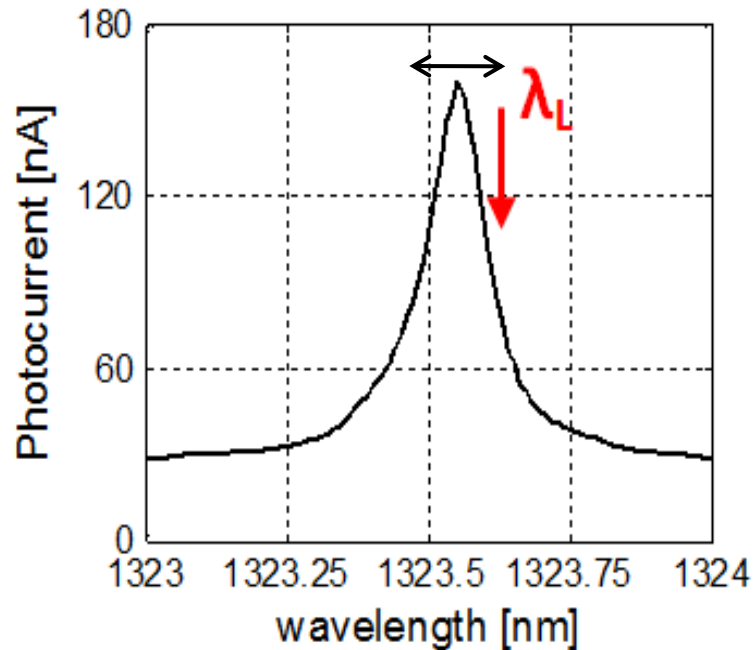
## Measuring thermal motion:



$f_1 = 2.18 \text{ MHz}$

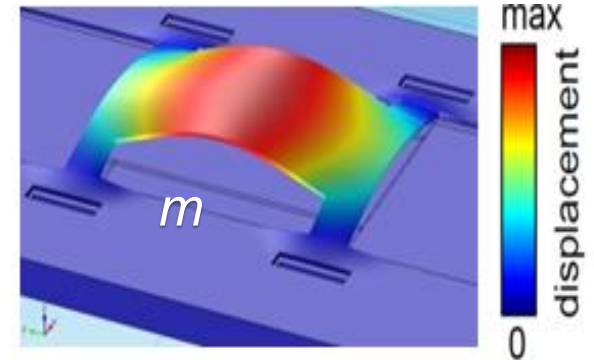
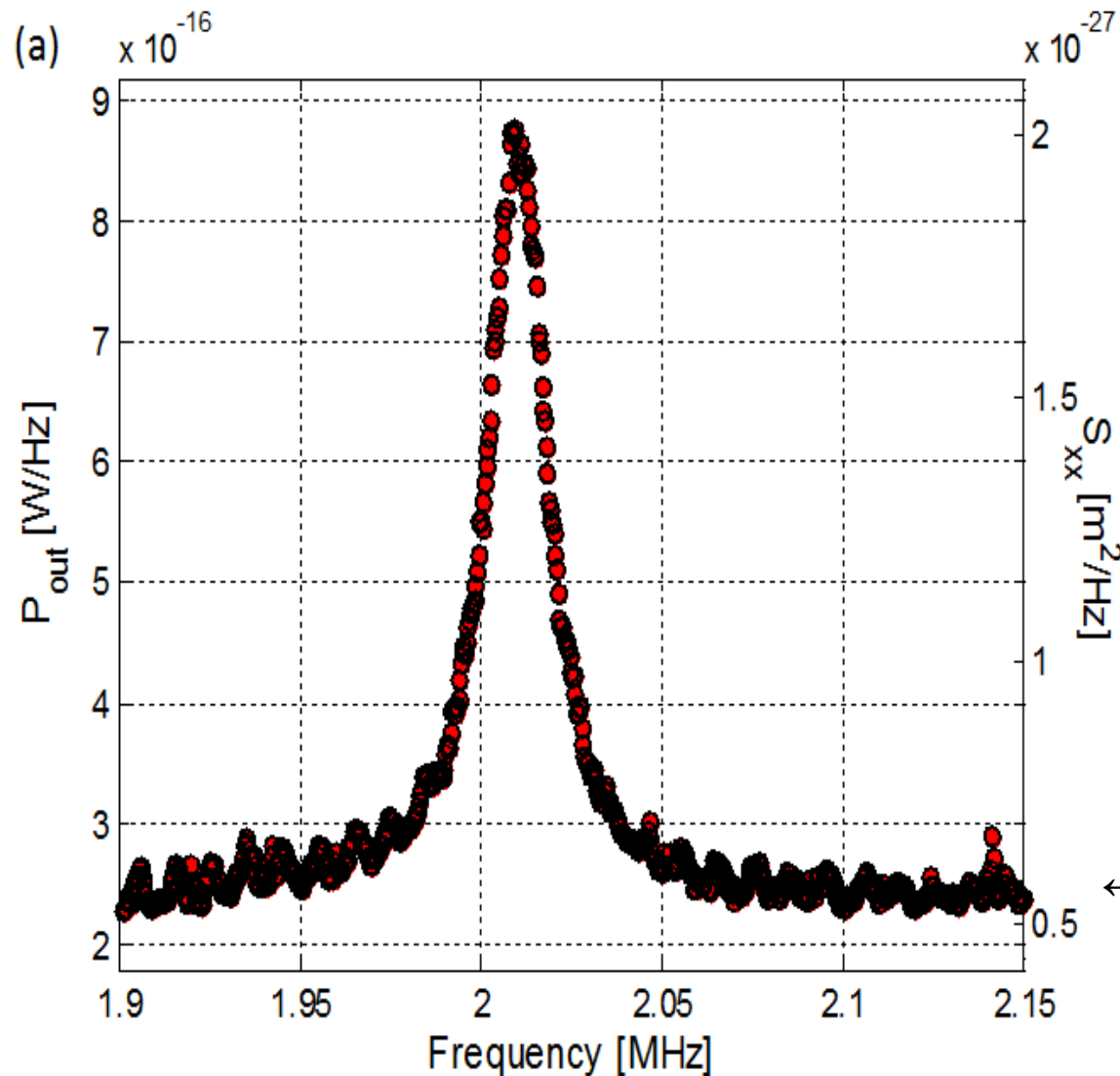
*Estimated amplitude of thermal motion:*

$$Z_{RMS} \approx 20 \text{ pm (@RT)}$$





# Displacement sensor demonstration



$$f_1 = 2.18 \text{ MHz}$$

*Estimated amplitude of thermal motion:*

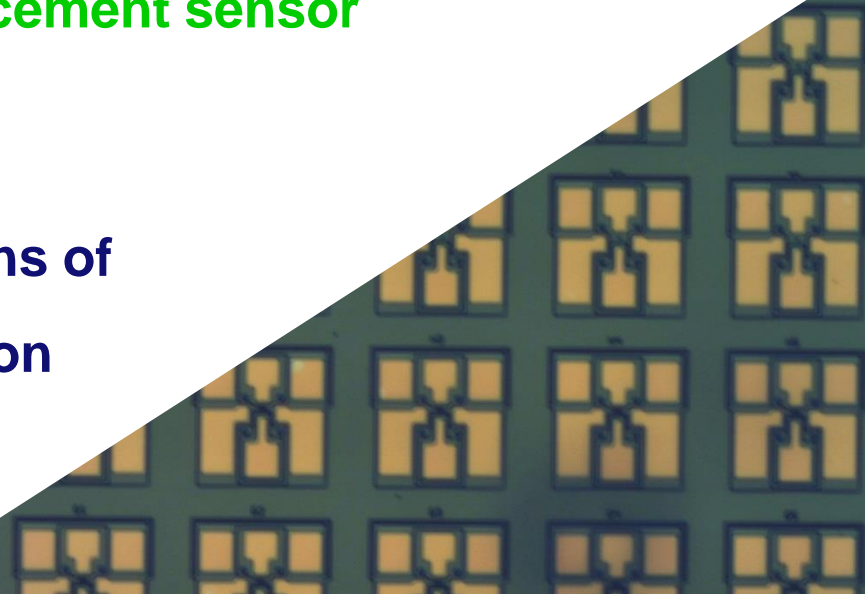
$$z_{RMS} \approx 20 \text{ pm (@RT)}$$

← *Sensitivity < 100 fm/(Hz)<sup>1/2</sup>*

# Conclusions

- ✓ **μ-spectrometer** with resolution down to **80 pm** over a range of up to **23 nm**
- ✓ Resonance modulation scheme with high rejection ratio (**30dB**) and resolution (**<1 pm** when used as a **wavemeter**)
- ✓ Application as **gas sensor** (HF detection)
- ✓ Fully integrated optomechanical **displacement sensor**

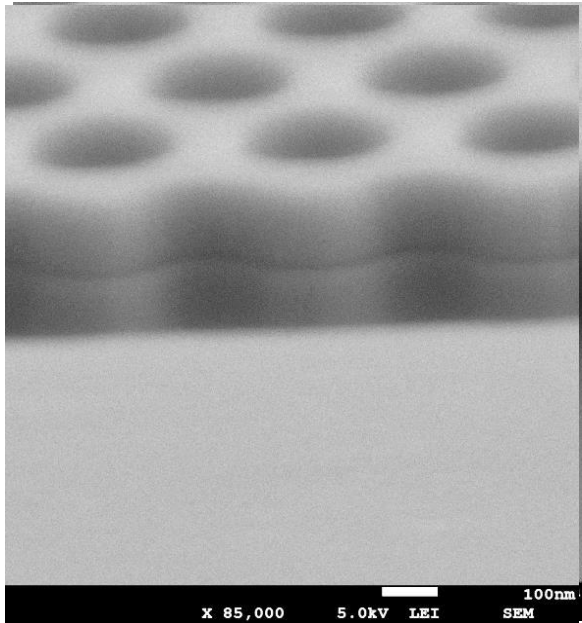
**All this in an integrated device, few tens of μm in size, suitable for mass production**



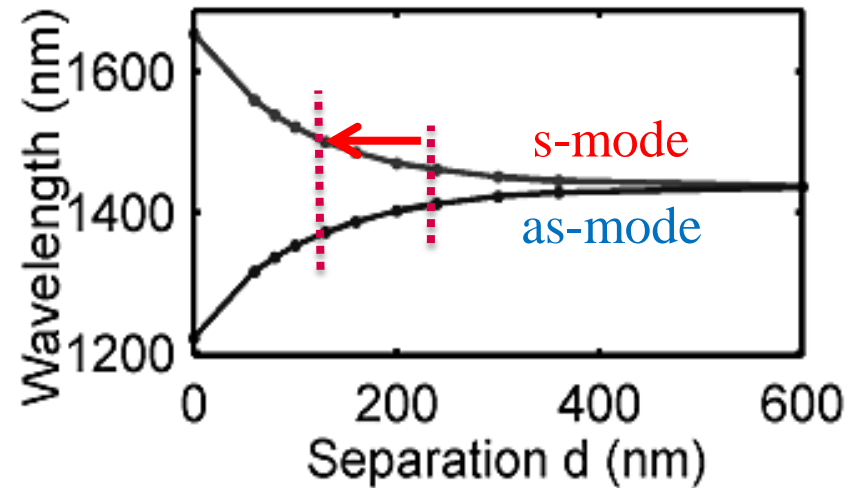
# Questions?

# Tuning: pull-in limitation

- Tuning is limited by pull-in effect to 2/3 of nominal distance



M.Cotrufo



*Simulation:* Tuning from  $d = 240$  nm to 160 nm provides:  $\Delta\lambda = 28$  nm

- Pull-in effect is **not reversible**

# Displacement sensor demonstration- Measuring Brownian motion

Experimental:  $\langle x^2 \rangle_{th} = \int S_{xx} df = (6.3 \text{ pm})^2$

Model:  $k_B T / m_{eff} \Omega_M^2 = (22 \text{ pm})^2$

- Transduction currently limited
- by diode speed ( $f_{\text{cut-off}} < f_1$ )
- To be addressed: Non-ohmic contacts

Displacement PSD:

$$S_{xx}(f) = \frac{P_{out}(f)}{Z A g_{OM}^2 \left( \frac{\partial I}{\partial \omega} \right)^2}$$

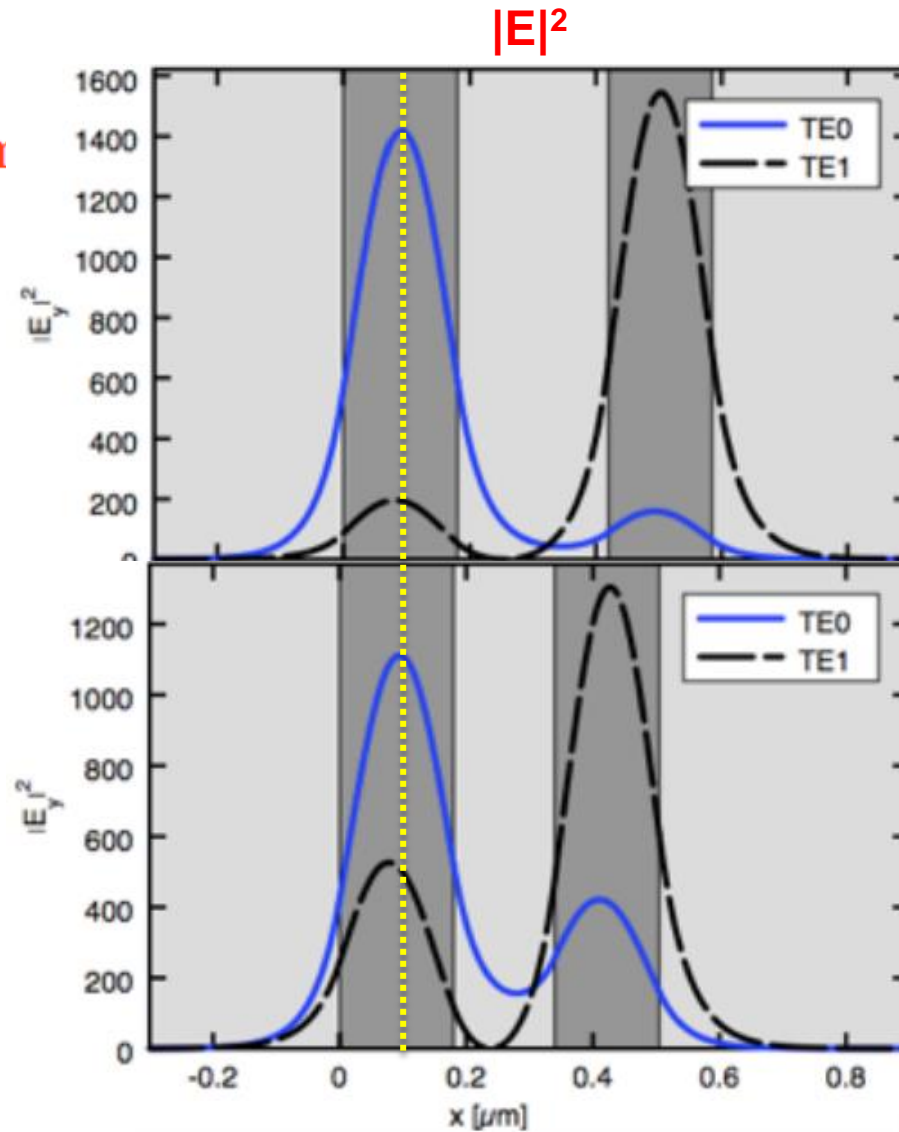
$$g_{OM} = \frac{\partial \omega}{\partial x} = 2 \cdot 10^{20} \text{ s}^{-1}/\text{m}$$

# Mode distribution in an asymmetric system

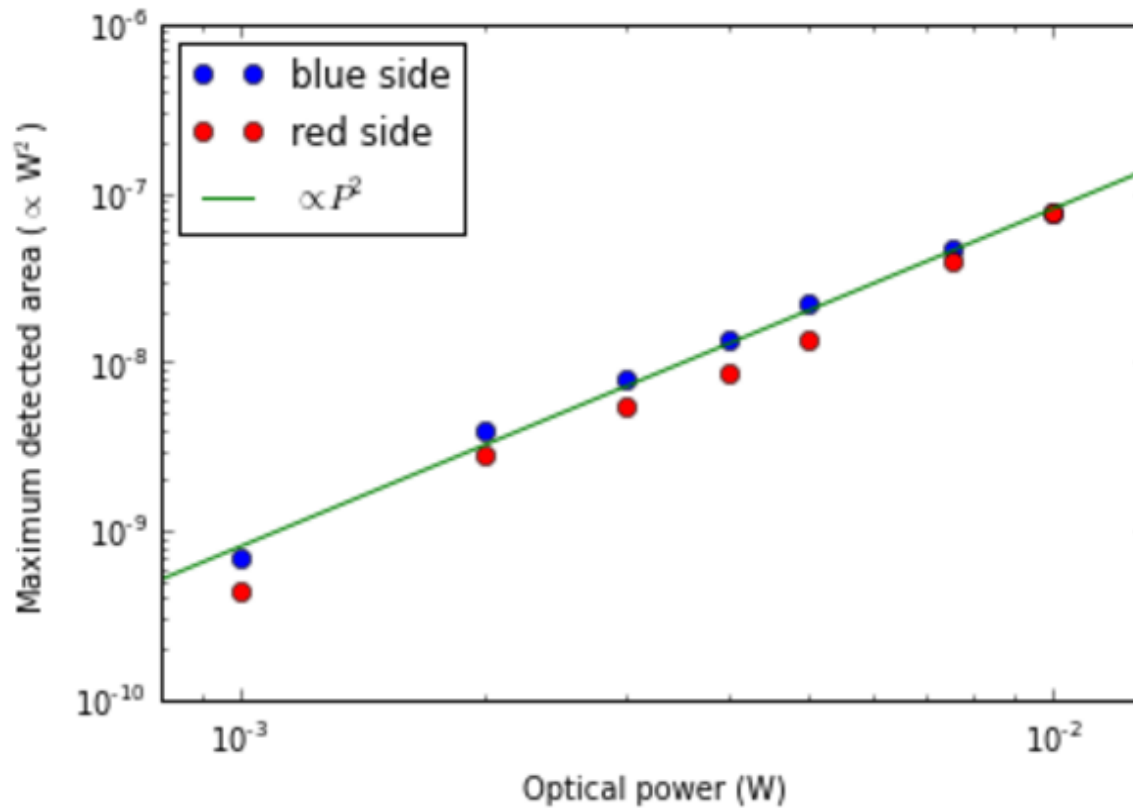
$t_1=180, t_2=165\text{nm}$

$d=240\text{nm}$

$d=160\text{nm}$



# Surface under the curve vs. laser power



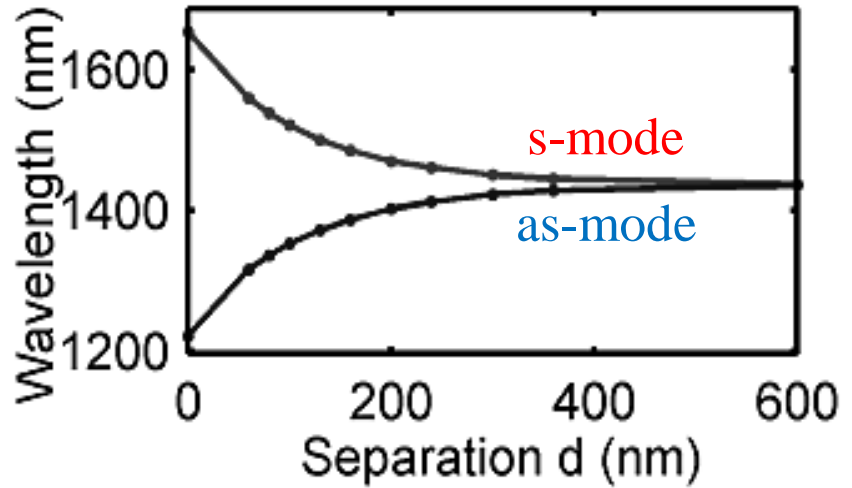
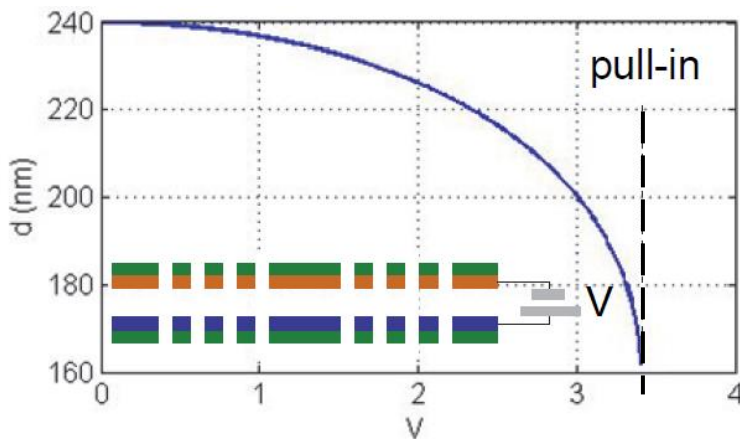
*R. Leijssen*

# Pull-in

- Tuning is limited by pull-in effect to 2/3 of nominal distance

$$\varepsilon = \underbrace{\frac{\varepsilon_0 S U^2}{2z}}_{\text{Electrostatic}} + \underbrace{\frac{k_+ (z - z_0)^2}{2}}_{\text{Elastic}}$$

$$\partial \varepsilon / \partial z = 0 \rightarrow z^3 - z^2 z_0 = -\frac{\varepsilon_0 S U^2}{2k_+}$$

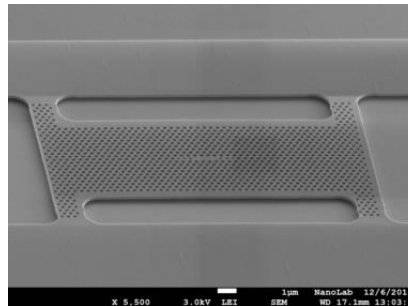


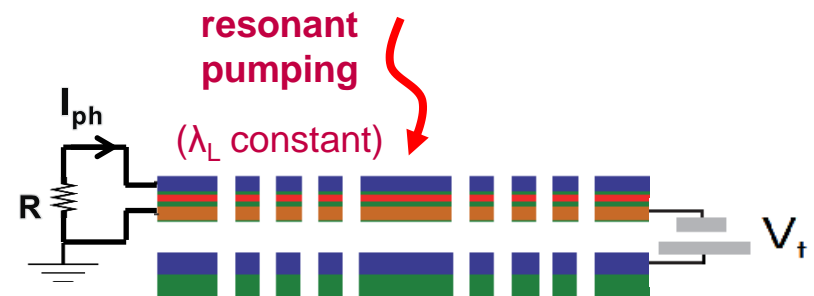
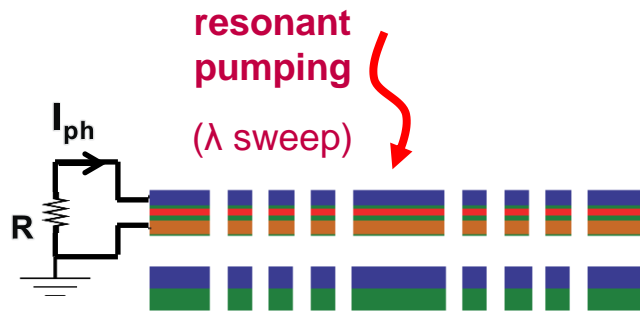
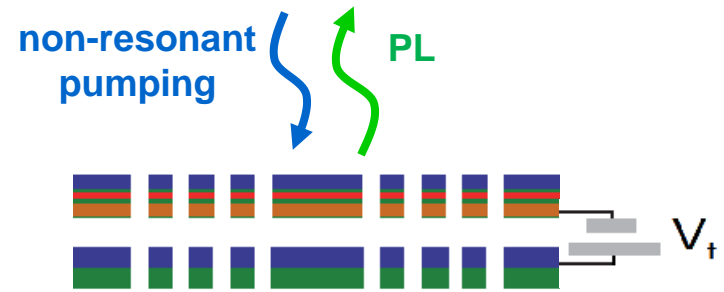
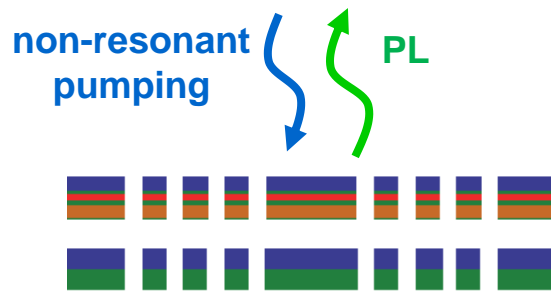
Simulation: Tuning from  $d = 240$  nm to 160 nm provides:  $\Delta\lambda = 28$  nm



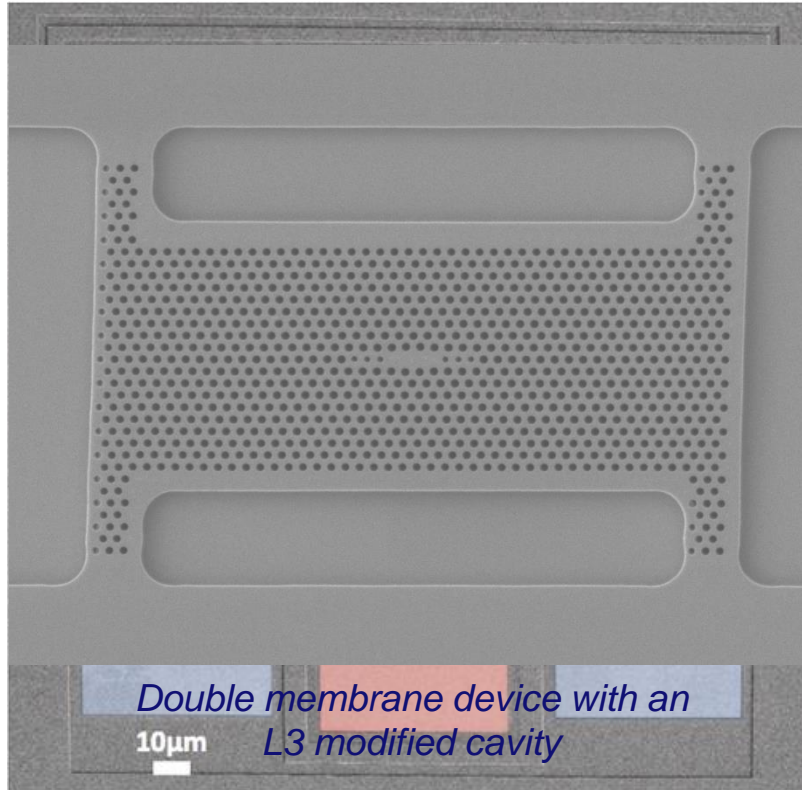
# Current status: $\mu$ -spectrometer progress

- Tuning range ( $\Delta\lambda$ ) > 50 nm → (7nm extended to 25 nm)
- Resolution ( $\delta\lambda$ ) < 100 pm → (76 pm)
- Free spectral range (FSR) > 50 nm → (up to 30 nm for H0 cavity)
- Responsivity = 0.05 A/W → (up to 0.02 A/W)
- Rejection ration > 15 dB → (30 dB)





# Fabrication of full devices:



*Double membrane device with  
highlighted contact pads*

\* M. Petruzzella

- ***Over 50 fabrication steps:***
- Multiple wet and dry etching steps
- 3 Optical lithography steps  
(for defining contact pad positions)
- Metal evaporation
- Electron beam lithography  
(for patterning the photonic crystal)